

DEVICE TECHNOLOGY & PACKAGING

Göran Alestig

- **MOS devices**
- **Silicon Bipolar technology**
- **Design and layout considerations**
- **GaAs and other III-V devices**
- **Packaging**
- **Reliability**

Manufacturing steps related to packaging:

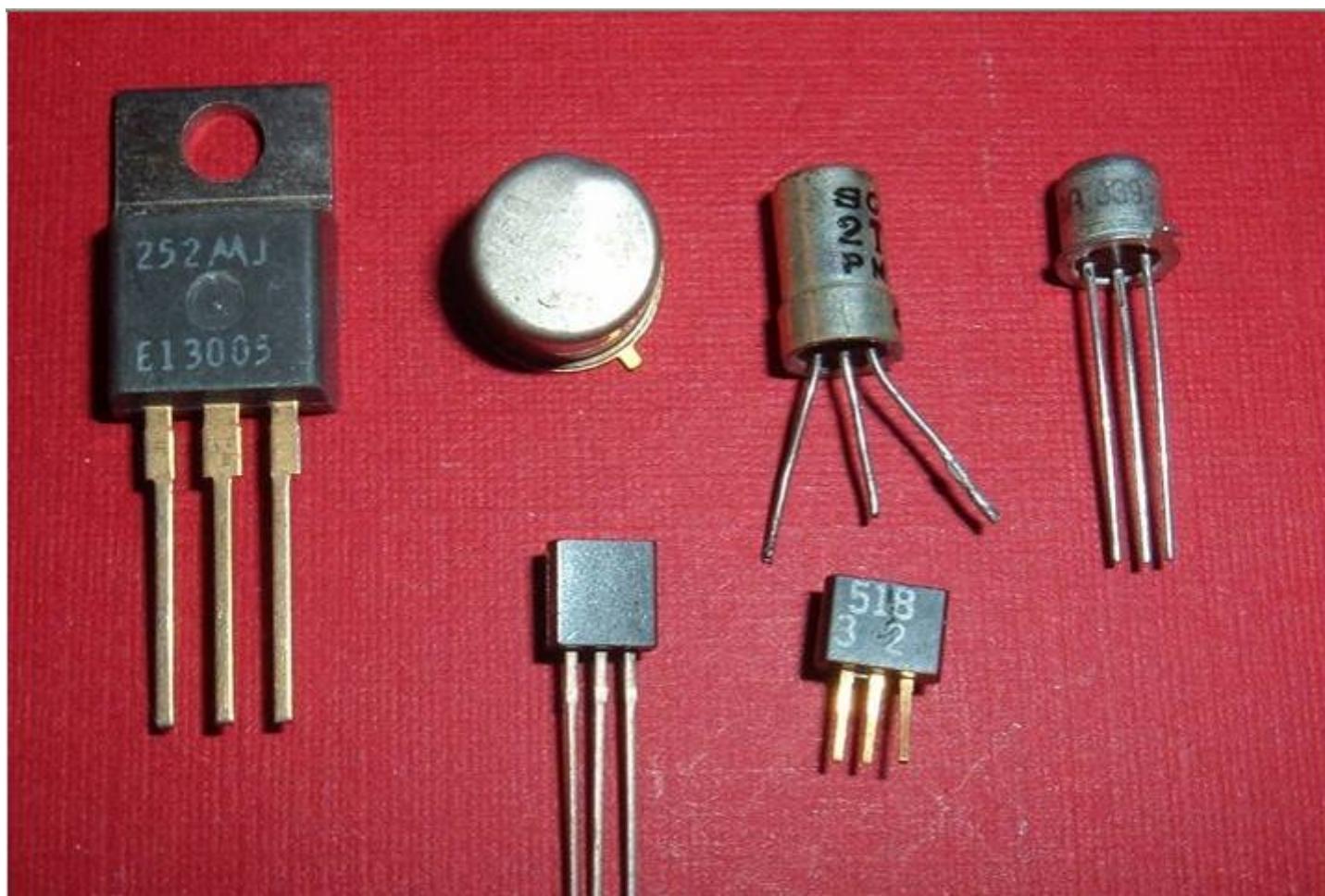
- **Testing**
 - On wafer before dicing
 - More complete test after packaging
- **Wafer thinning**
- **Die separation – Scribe or saw**
- **Die attachment – Epoxy or eutectic**
- **Wire bonding**
 - Ultrasonic or thermal
 - Ball bonding or wedge bonding
- **Flip-chip and solder bump technology**



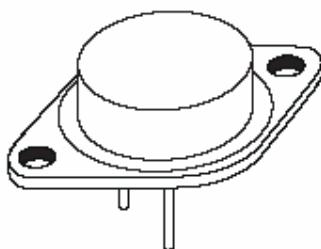
Figure 1. Example of an IC Tester (Left) and Three (3) Examples of Test Handlers (Right)



Placement: CMP/dicing room
The Loadpoint Microace 3+ diamond saw is used to dice processed wafers etc. into chips. It can cut just about anything that is thinner than 3 mm. It can divide a wafer in 2 dimensions automatically.



**TRANSISTOR
OUTLINE PACKAGE**

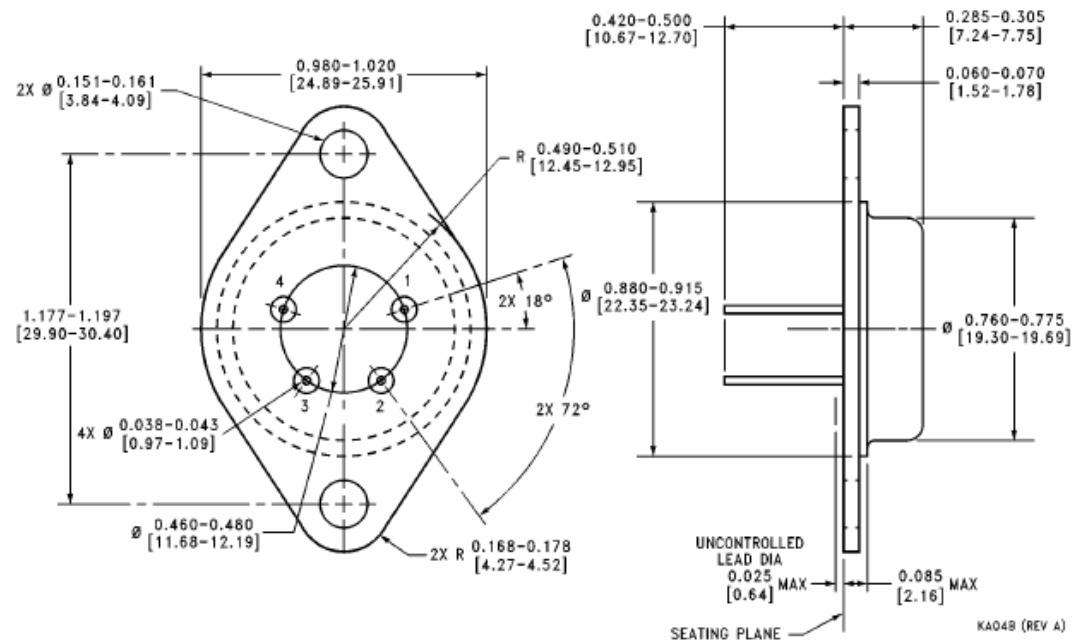


TO-3

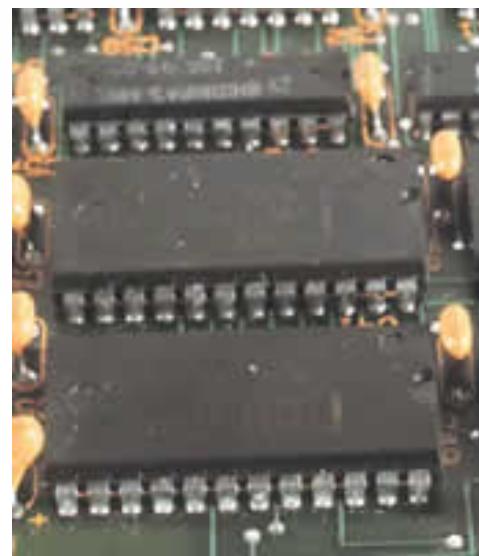
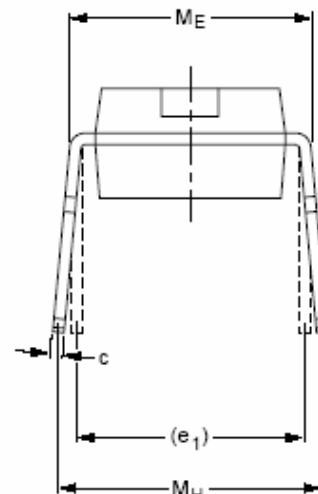
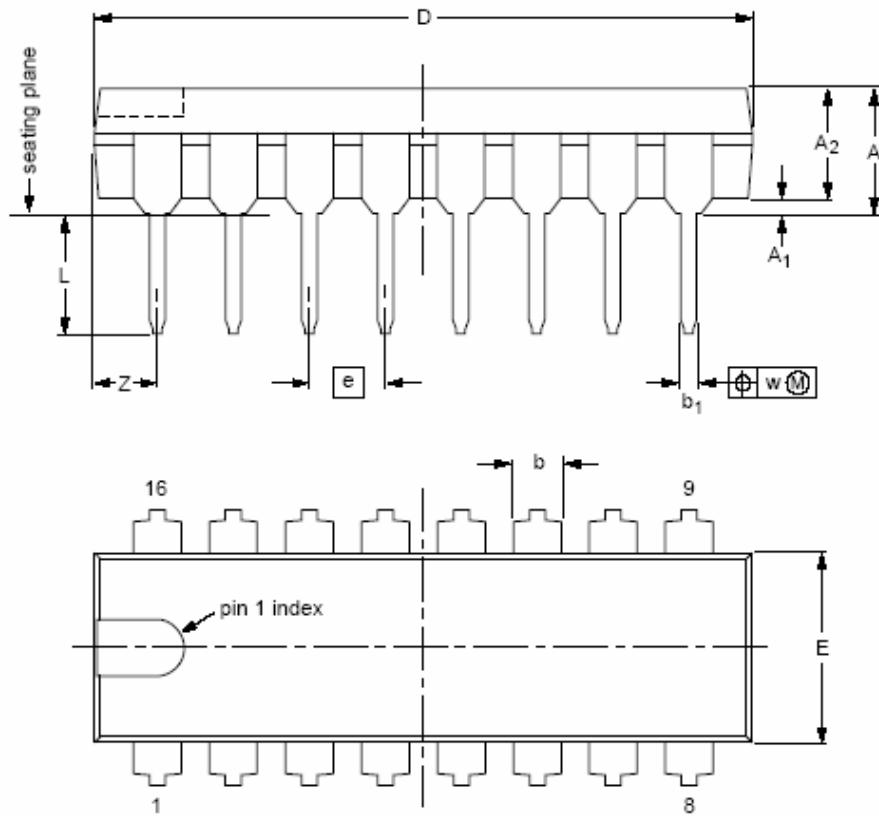
National Semiconductor

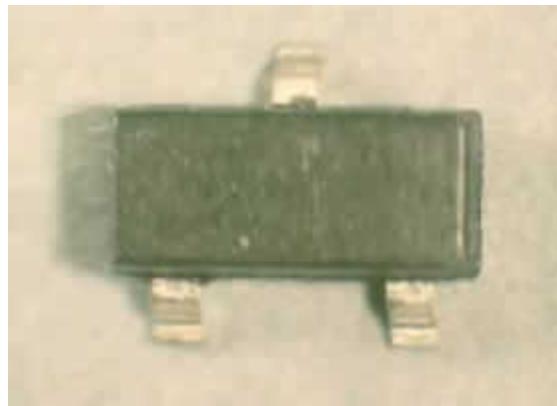
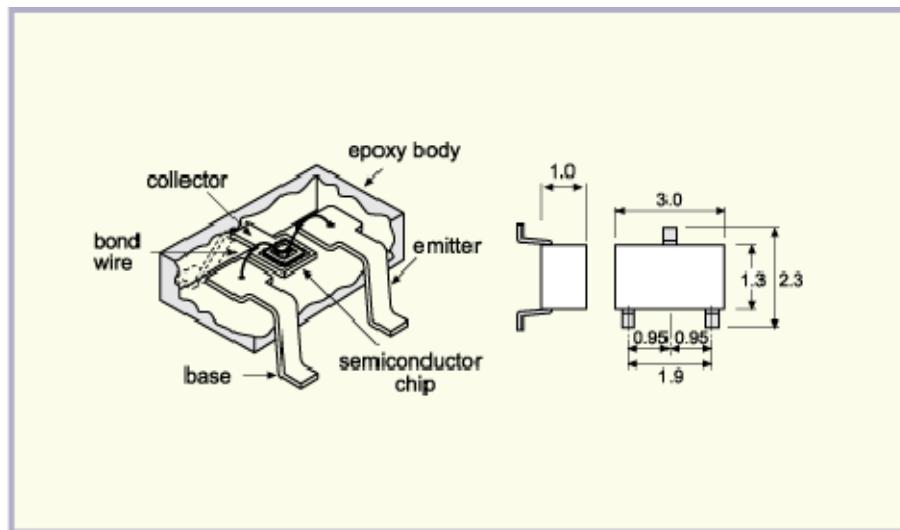
June 1993

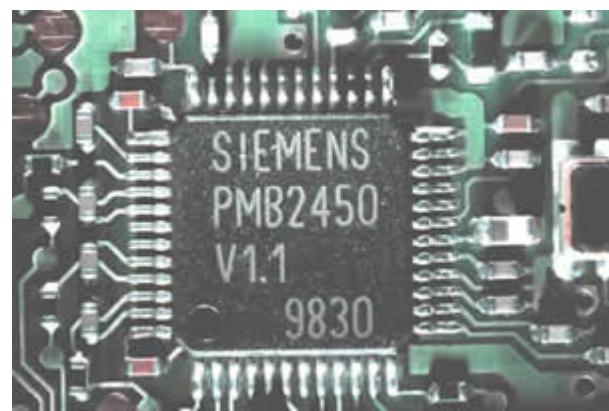
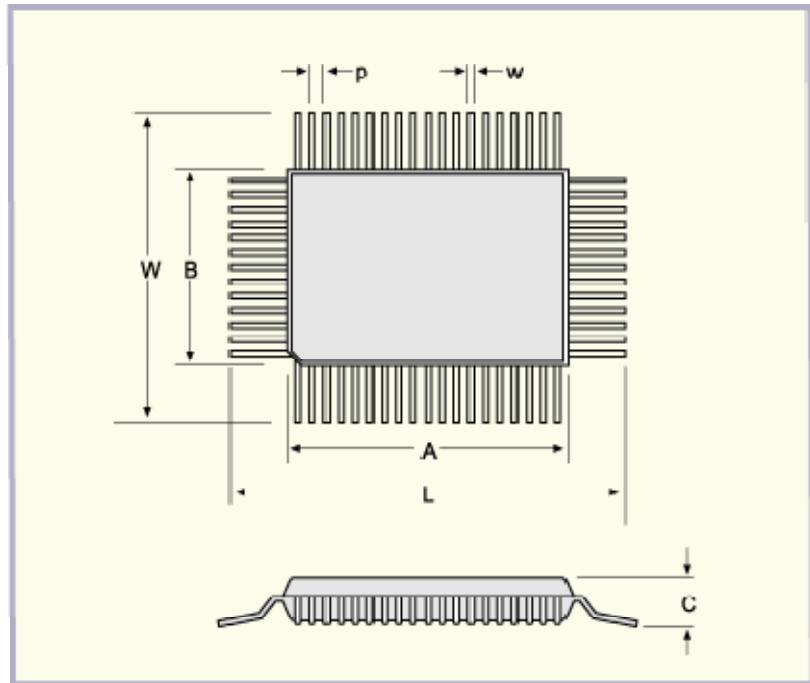
**4 Lead TO-3 Metal Can Package, Low Profile
NS Package Number KA04B**

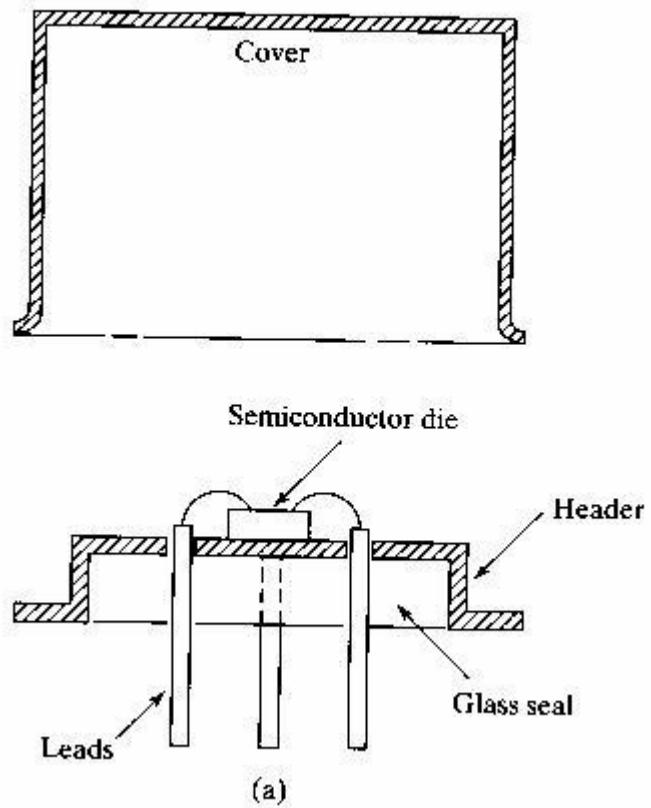
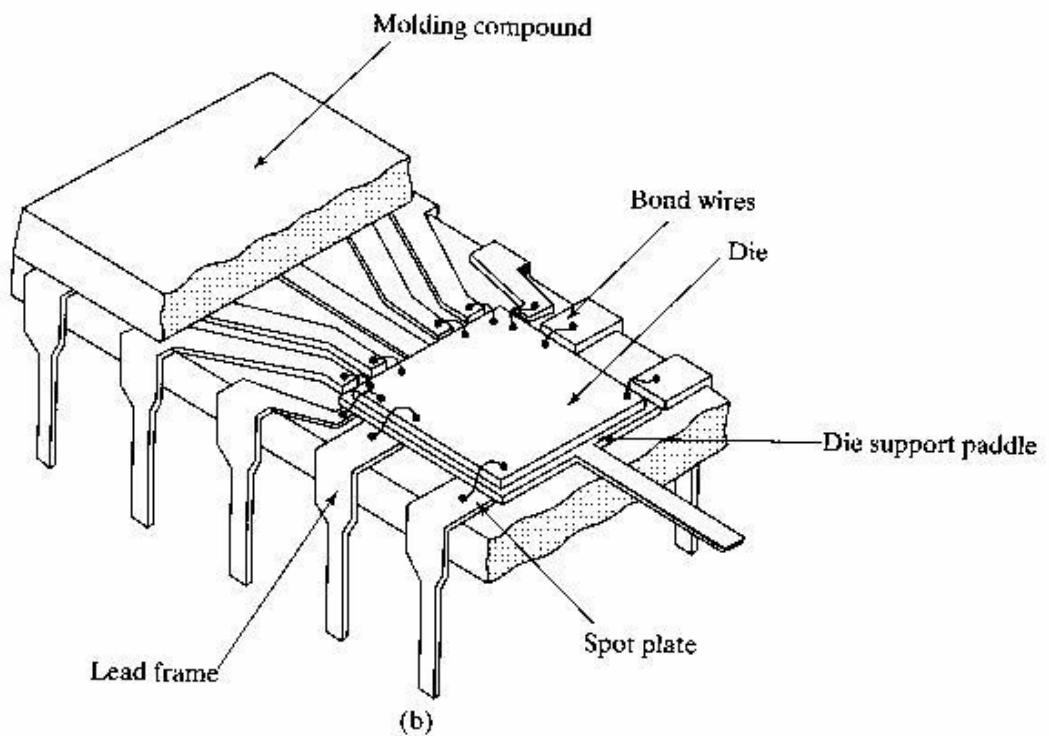


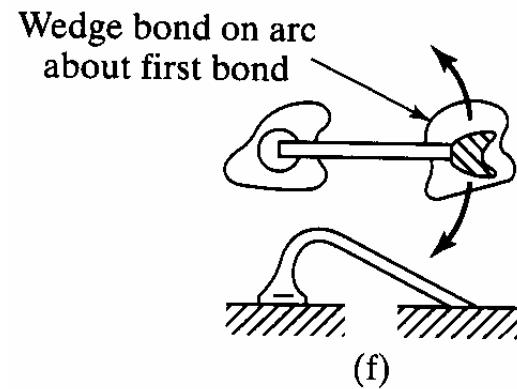
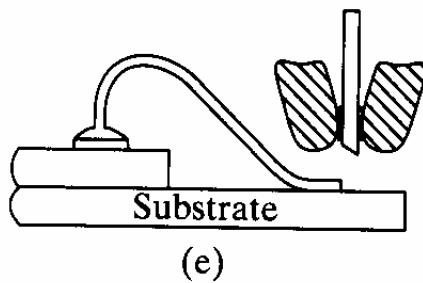
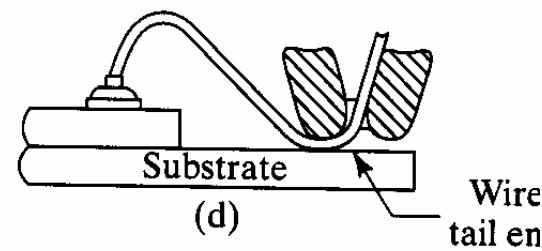
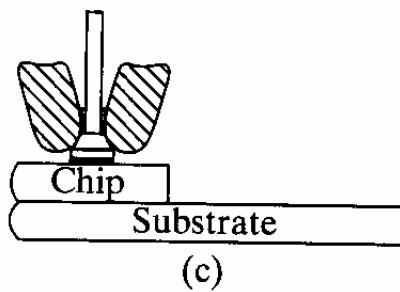
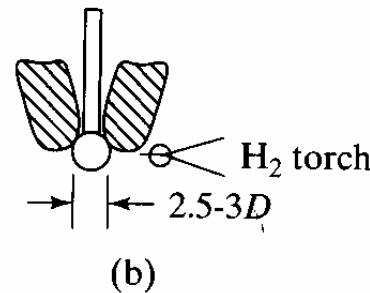
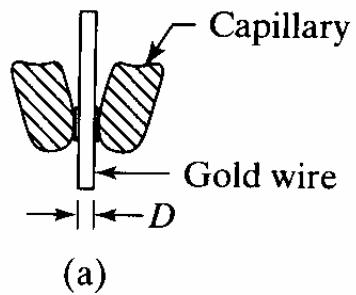
All dimensions are in inches (millimeters)



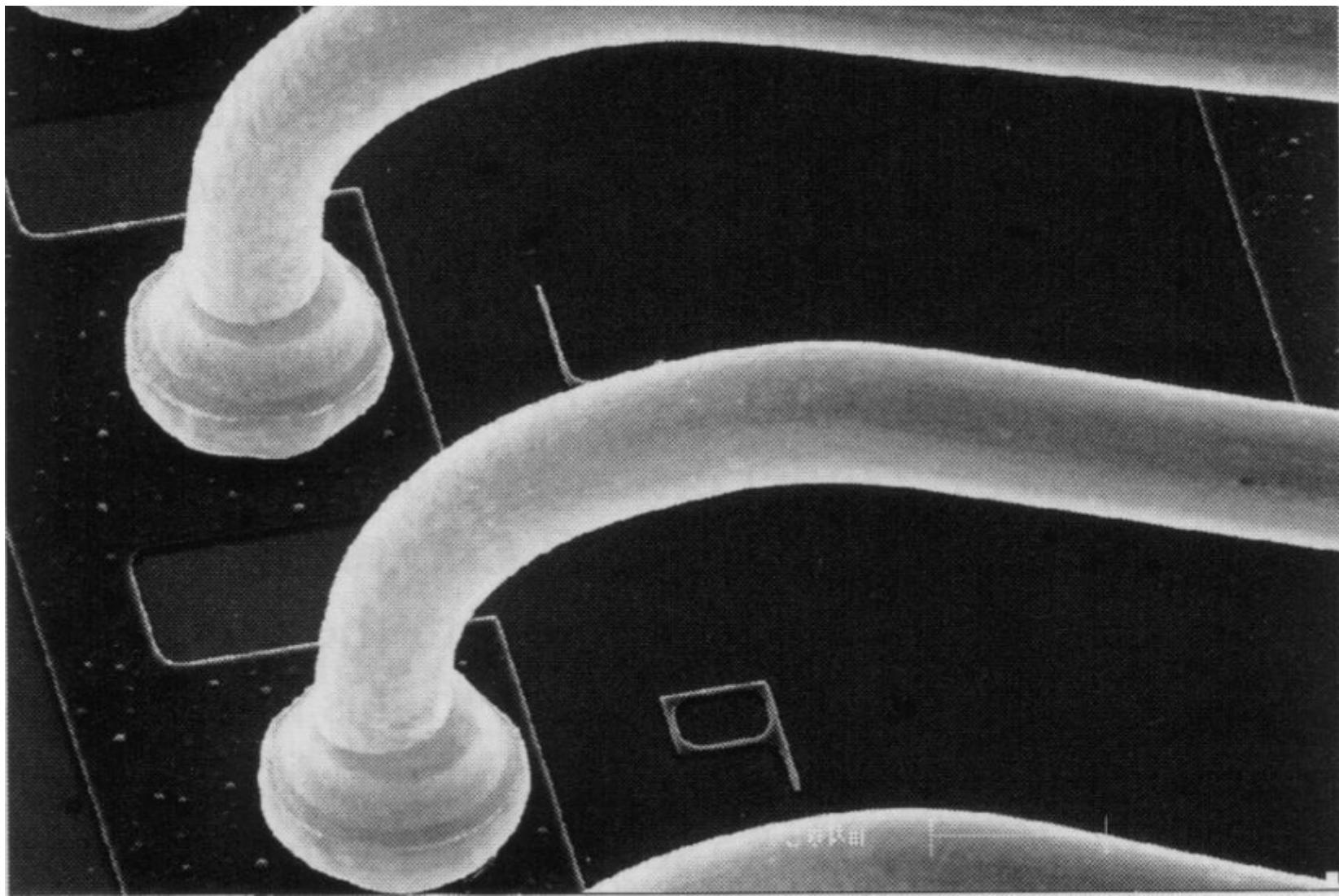






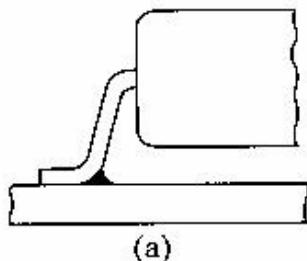


CHALMERS

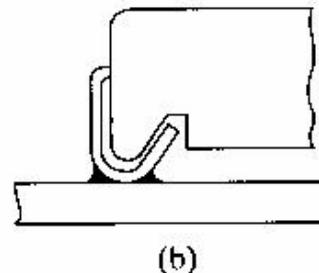


FKA195

MC2



(a)



(b)



(c)

Small outline transistor (SOT)



(d)

Small outline integrated circuit (SOIC)



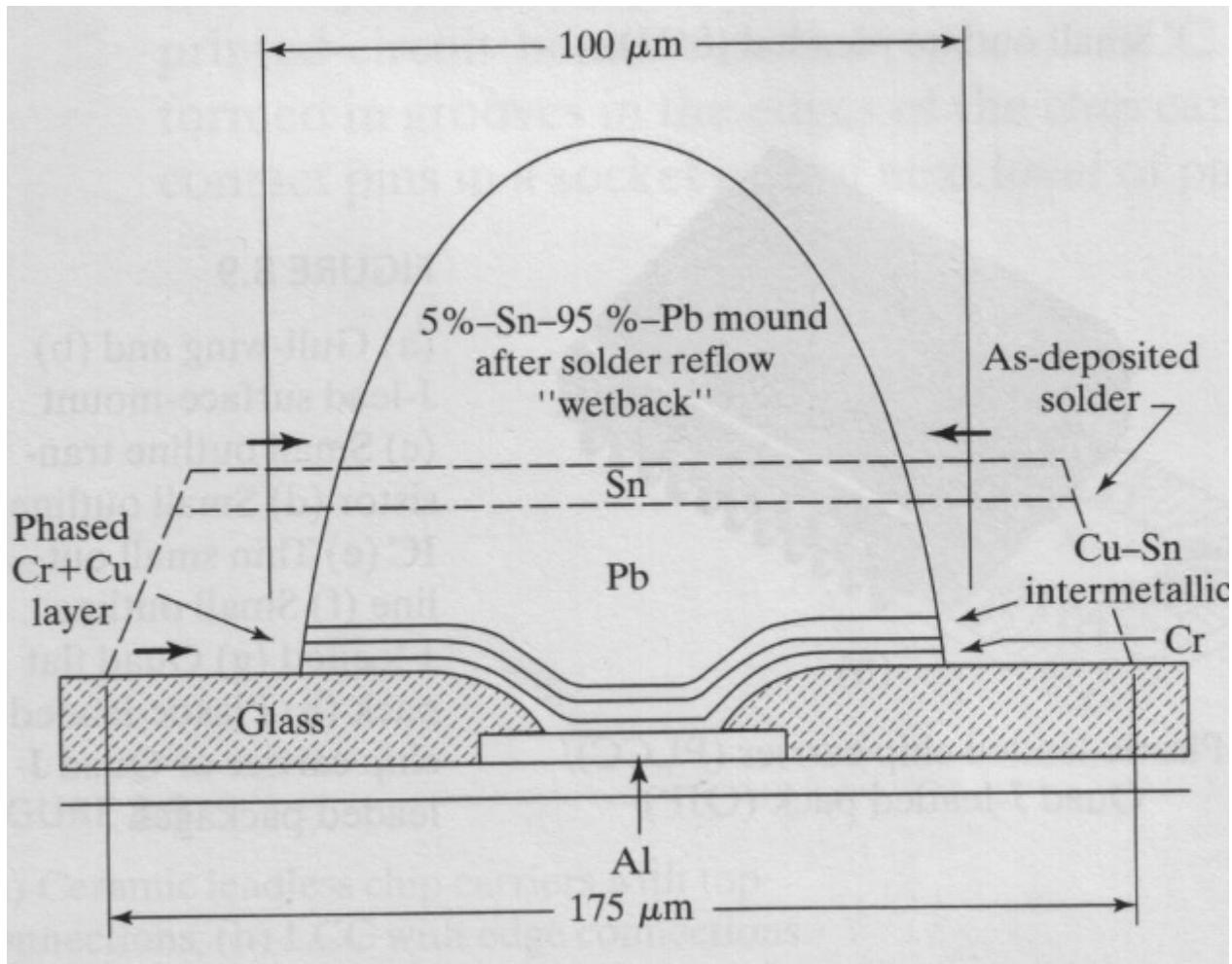
(e)

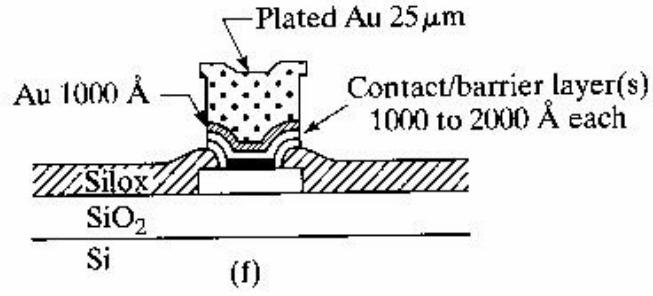
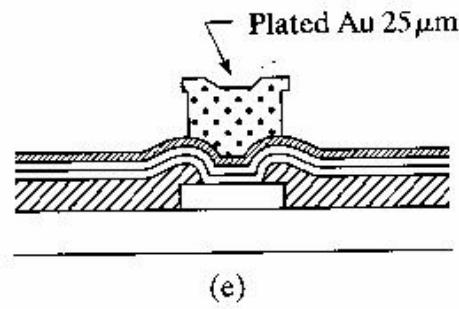
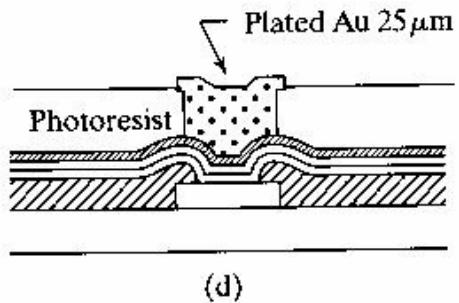
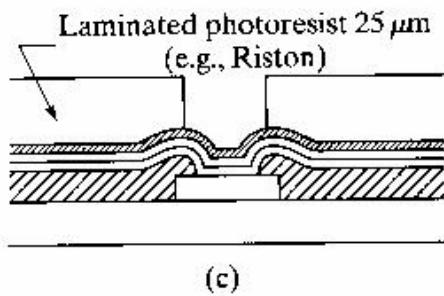
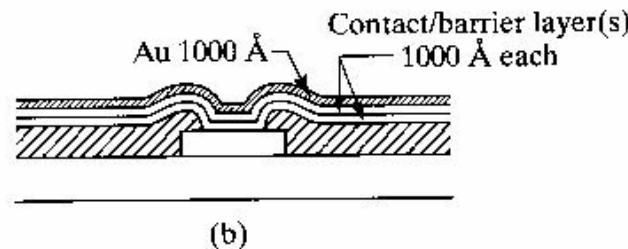
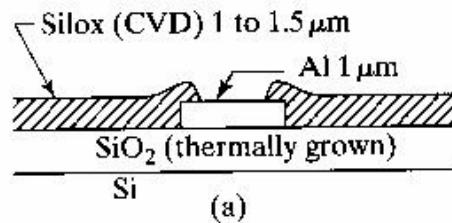
Thin small outline package (TSOP)

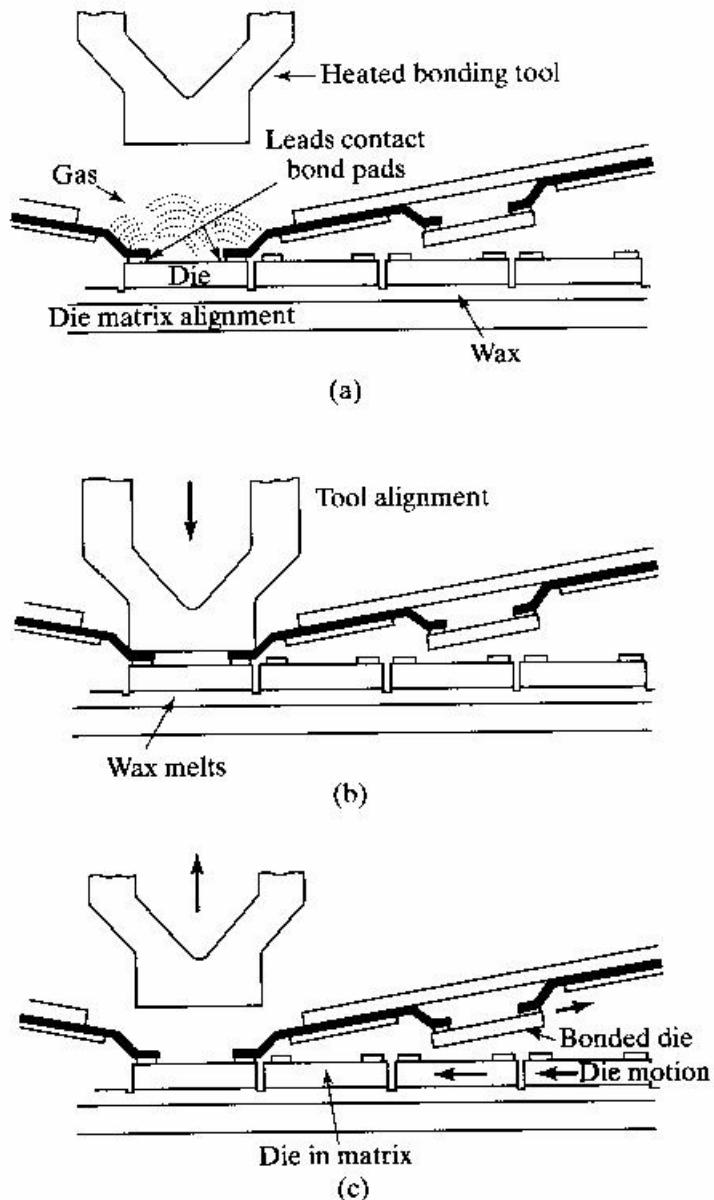


(f)

Small outline j-leaded (SOJ)







**TAB = Tape
Automated
Bonding**

DEVICE TECHNOLOGY & PACKAGING

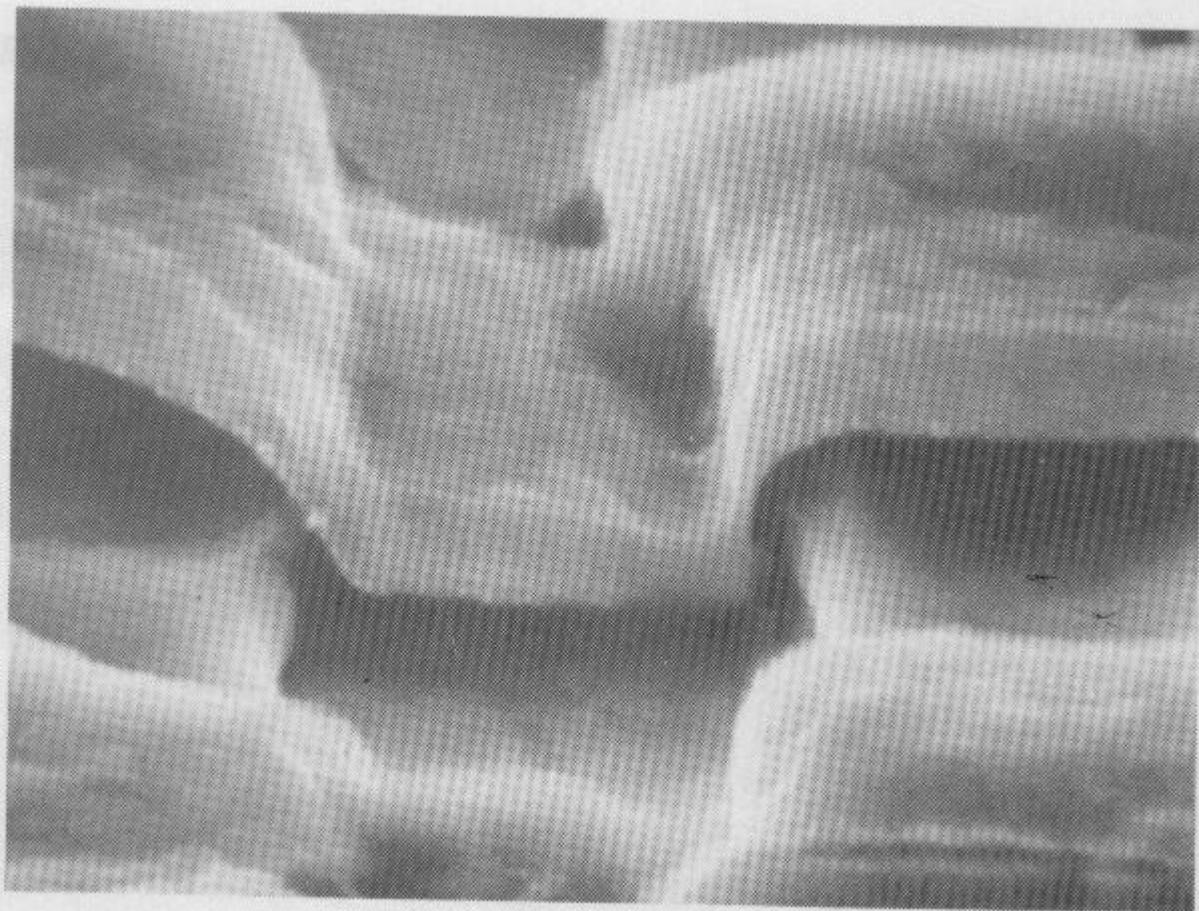
Göran Alestig

- **MOS devices**
- **Silicon Bipolar technology**
- **Design and layout considerations**
- **GaAs and other III-V devices**
- **Packaging**
- **Reliability**

Reliability

- Needs to be "designed in", cannot be added afterwards
- Need to pass tests for:
 - Current density
 - Voltage stress (dielectric breakdown, hot electrons, ...)
 - Step coverage of metal lines
 - Hot/cold temp stress
 - Passivation integrity
 - ESD (electro-static discharge)
 - etc, etc,

CHALMERS



FKA195

MC2

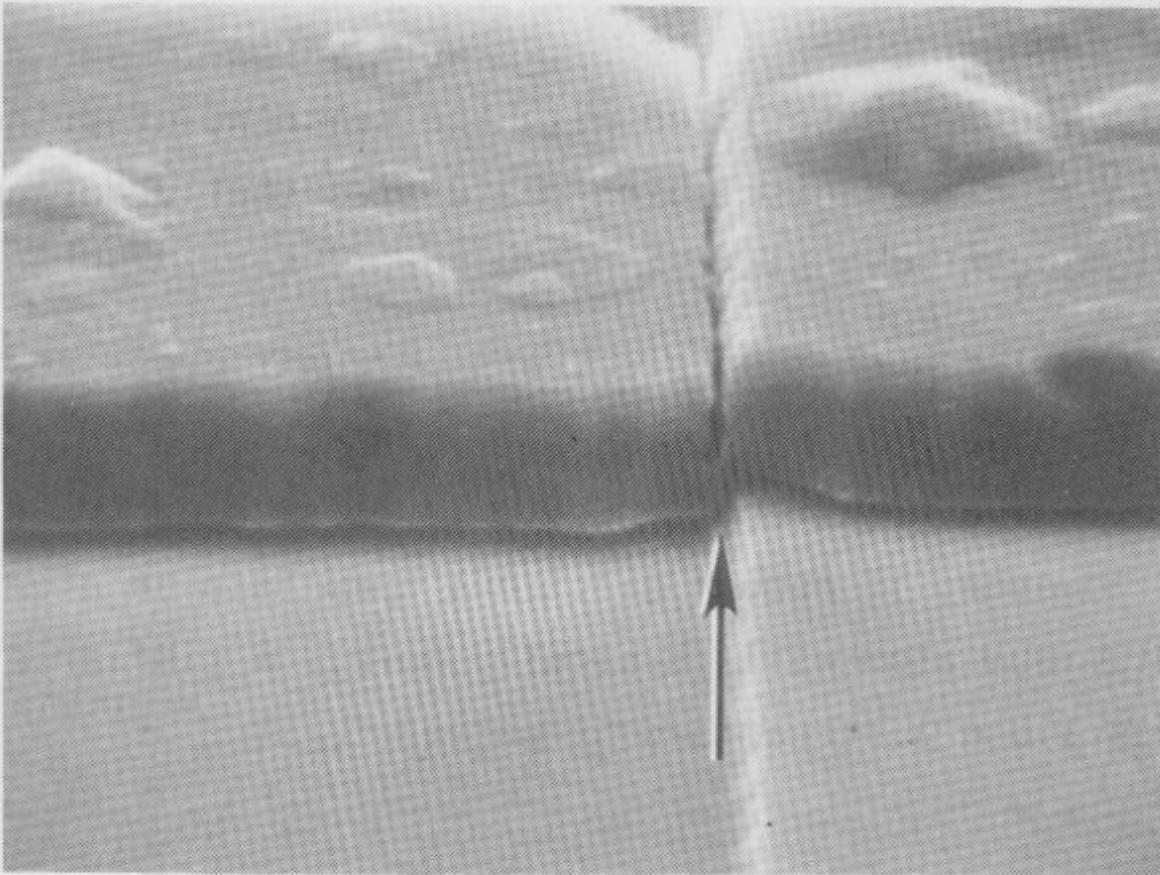
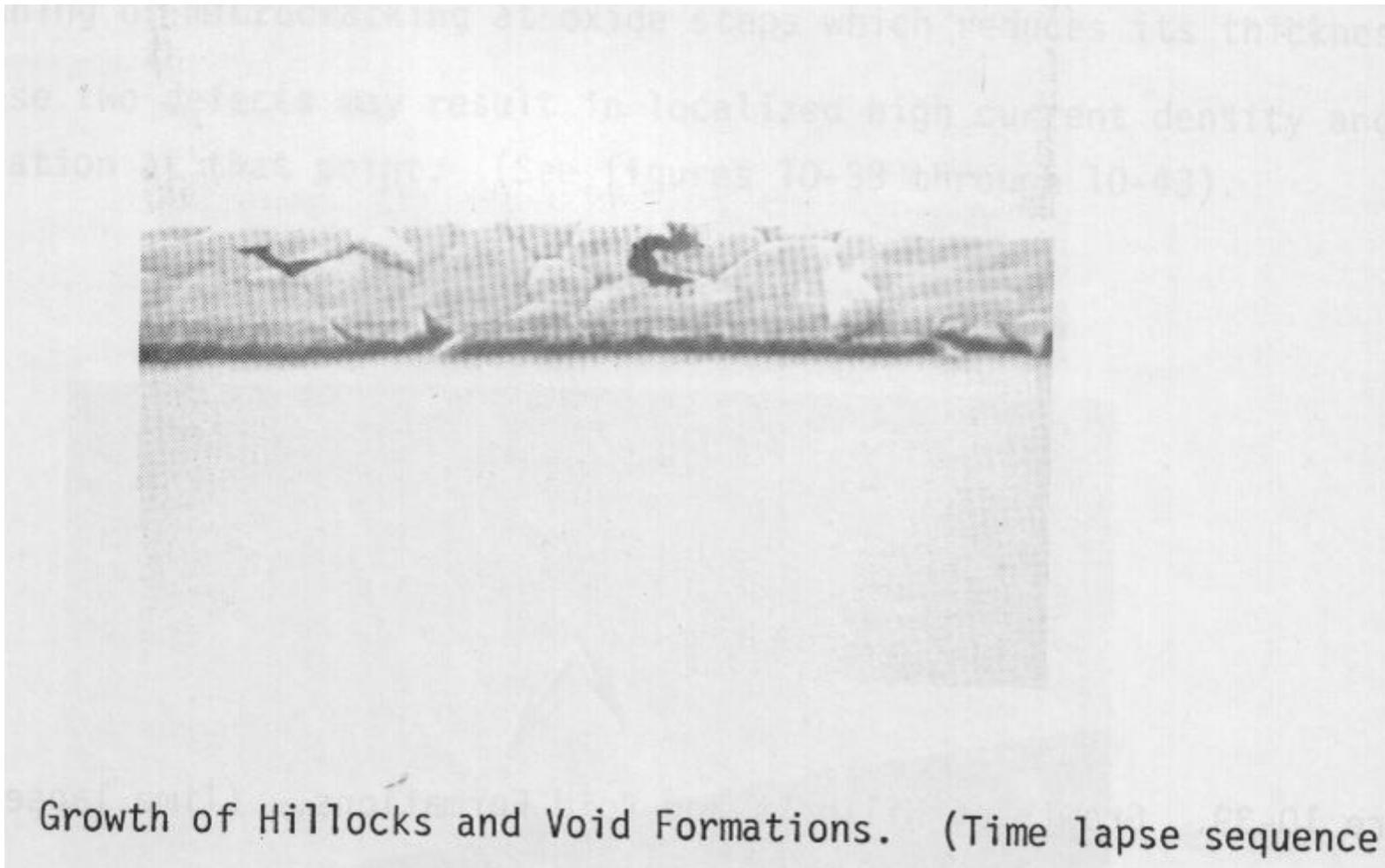
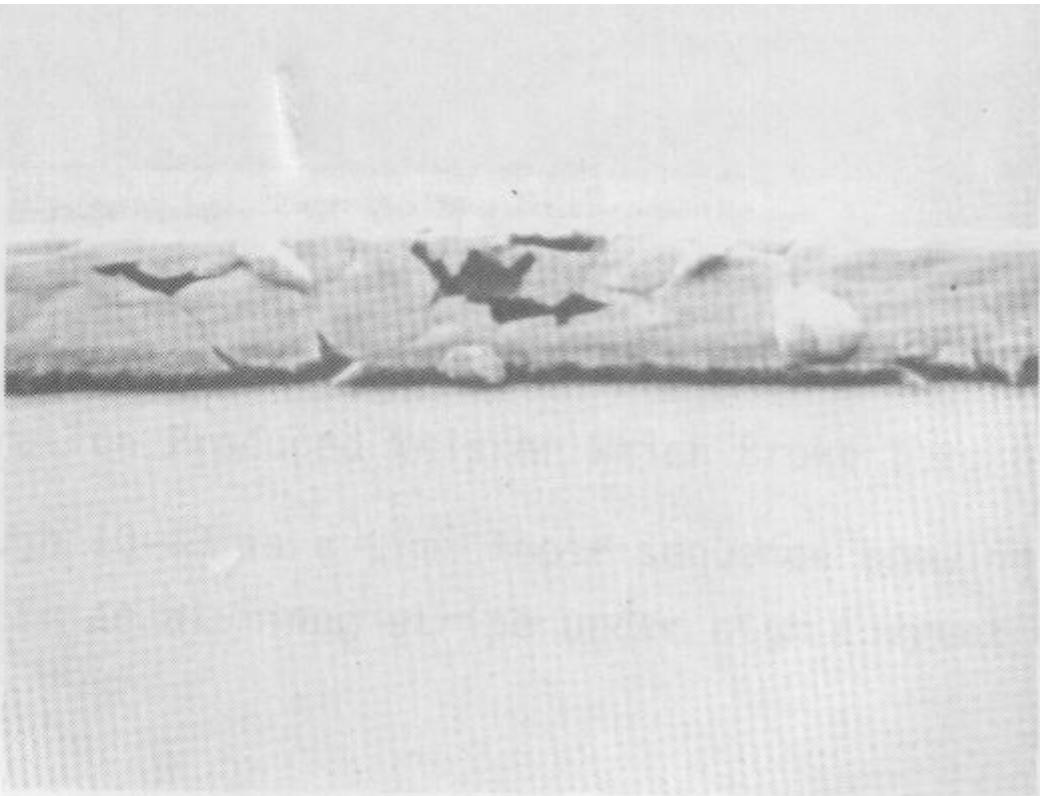


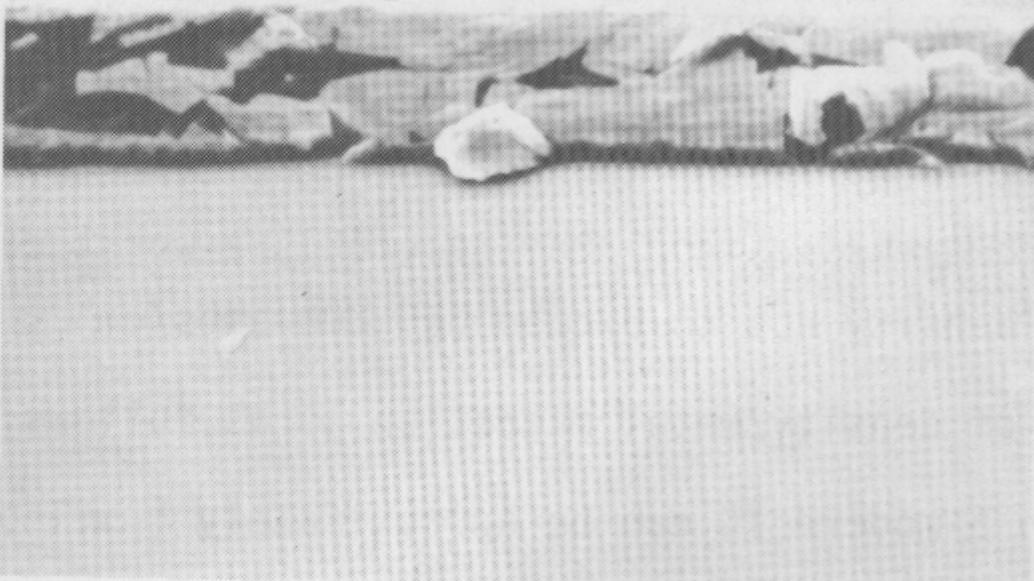
Figure 10-33. Excellent Example of Microcrack Propagation up Thru a Very Thick Metal Layer. Metal is 4 to 5 times as Thick as the Step is High.



Growth of Hillocks and Void Formations. (Time lapse sequence)



Growth of Hilllocks and Void Formations. (Time lapse sequence 4)



Growth of Hillocks and Void Formations. (Time lapse sequence 5)

